

Computer-Aided Design of MEMS

Eigenvalues, Energy Losses,
and Dick Tracy Watches

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Outline

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MEMS Basics

Anchor loss

Thermoelastic damping

Filter design

Conclusions

- MEMS (Micro-Electro-Mechanical Systems) basics and RF (Radio Frequency) MEMS
- Disk resonators and perfectly matched layers
- Beam resonators and thermoelastic damping
- Model reduction, mode tracking, and optimization
- Conclusions

What are MEMS?

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» Micromechanical filters

» Damping and Q

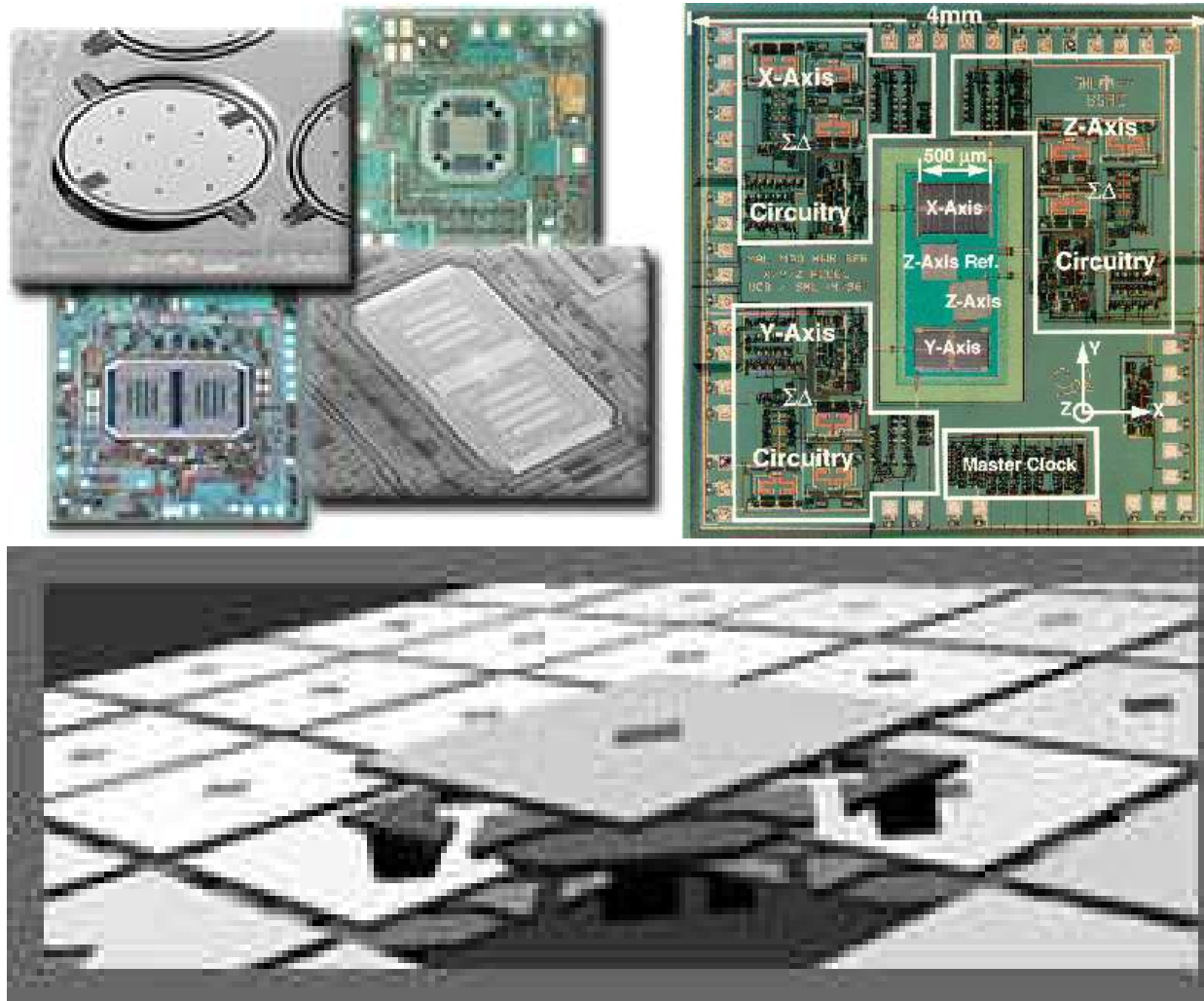
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- Micro-electro-mechanical systems
 - ◆ Chemical, fluid, thermal, optical (MECFTOMS?)
- Applications:
 - ◆ Sensors (inertial, chemical, pressure)
 - ◆ Ink jet printers, biolab chips
 - ◆ RF devices: cell phones, inventory tags, pico radio
 - ◆ “Smart dust”
- Use integrated circuit (IC) fabrication technology
- Large surface area / volume ratio
- Still mostly classical (vs. nanosystems)

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300 μm

1. Si wafer

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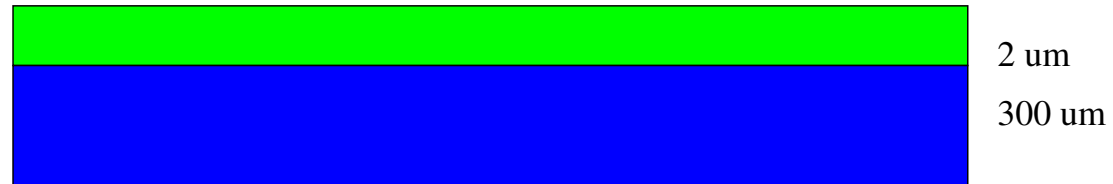
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1. Si wafer
2. Deposit 2 microns SiO_2

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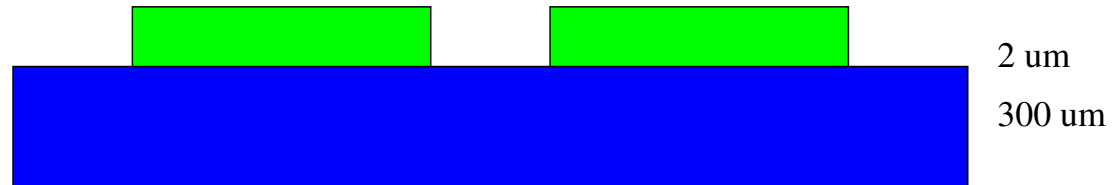
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1. Si wafer
2. Deposit 2 microns SiO_2
3. Pattern and etch SiO_2 layer

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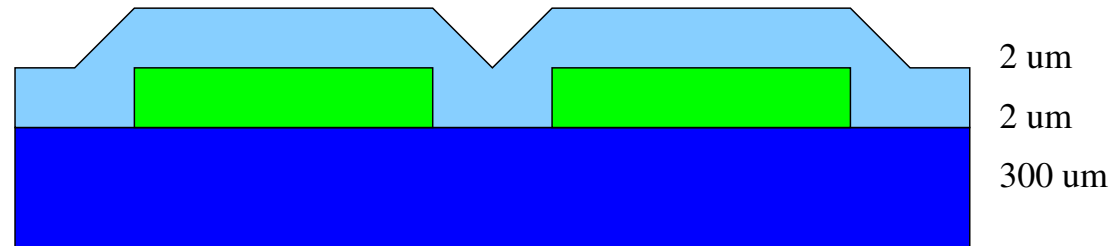
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1. Si wafer
2. Deposit 2 microns SiO_2
3. Pattern and etch SiO_2 layer
4. Deposit 2 microns polycrystalline Si

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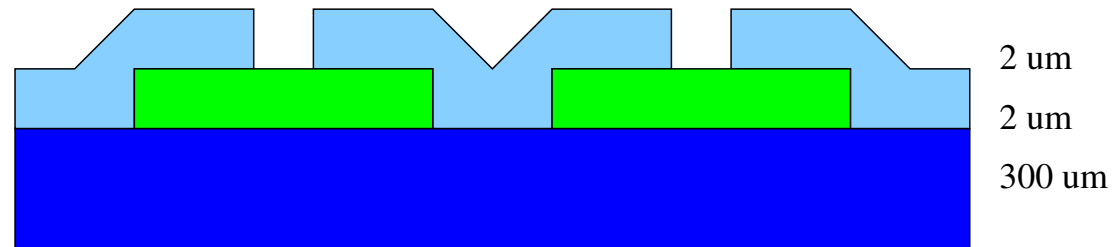
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1. Si wafer
2. Deposit 2 microns SiO₂
3. Pattern and etch SiO₂ layer
4. Deposit 2 microns polycrystalline Si
5. Pattern and etch Si layer

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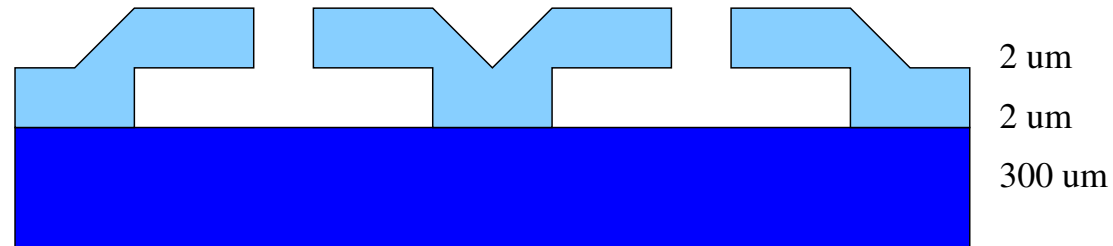
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1. Si wafer
2. Deposit 2 microns SiO_2
3. Pattern and etch SiO_2 layer
4. Deposit 2 microns polycrystalline Si
5. Pattern and etch Si layer
6. Release etch remaining SiO_2

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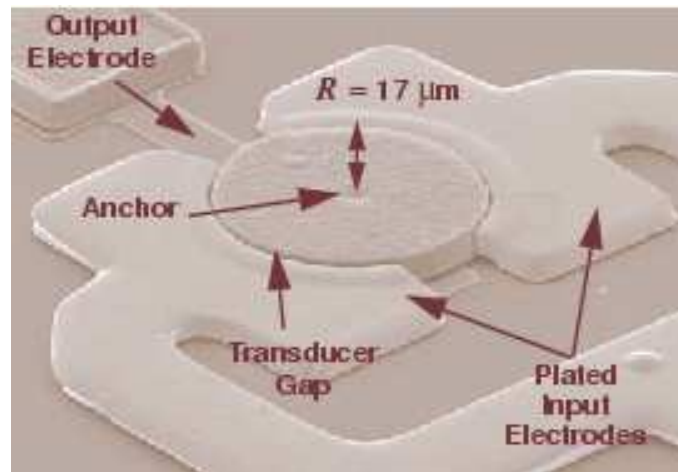
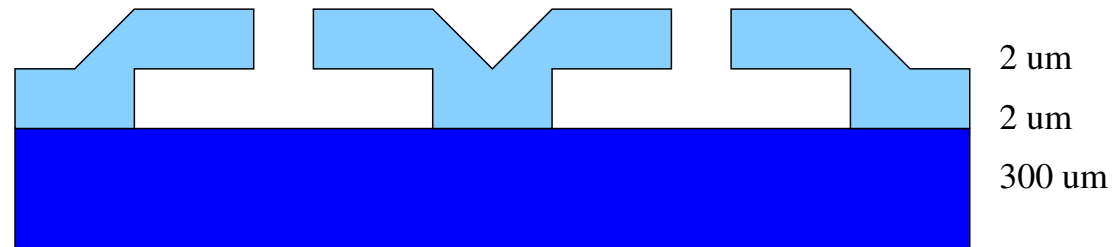
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(C. Nguyen, iMEMS 01)

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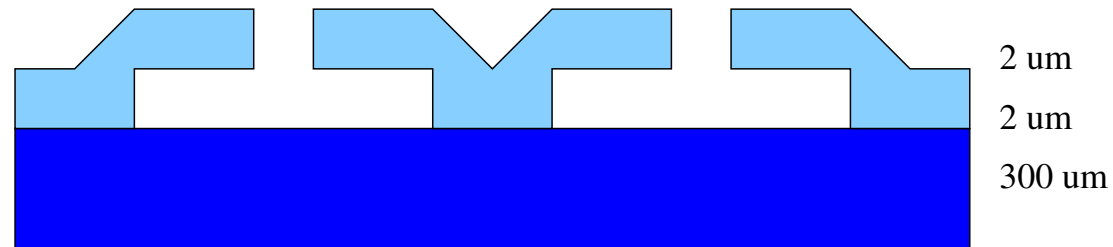
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- Characteristic dimensions: microns
- Geometry is “2.5” dimensional
- Relatively loose fabrication tolerances
- Difficult to characterize

RF MEMS

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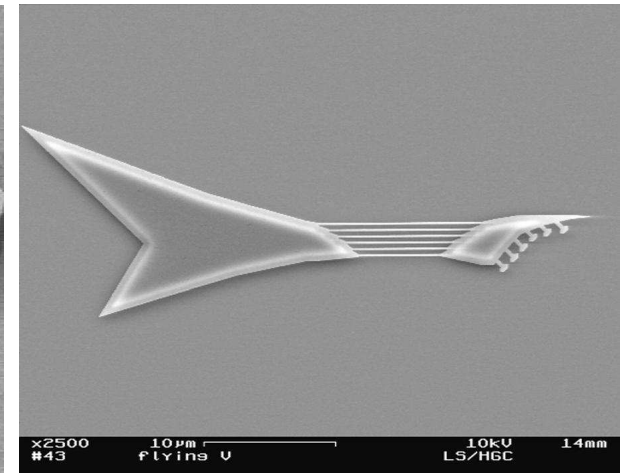
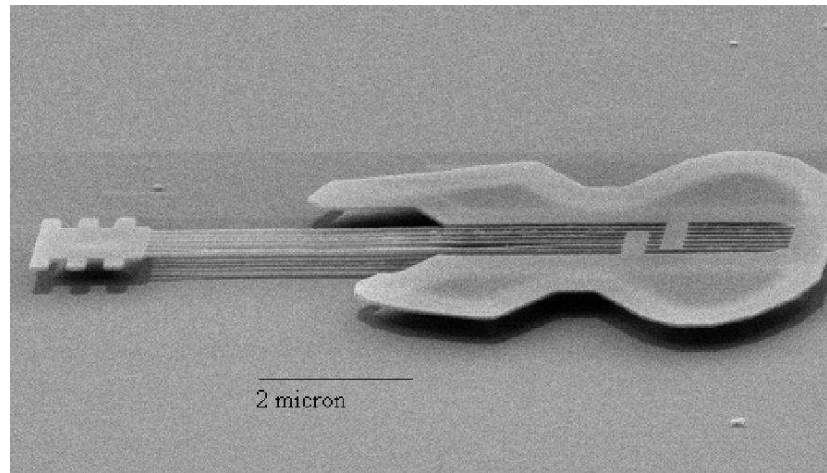
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Microguitars from Cornell University (1997 and 2003)

- MHz-GHz mechanical resonators
- Impact: smaller, lower-power cell phones
 - ◆ Replace quartz freq references, filter elements
 - ◆ Integrate into CMOS stack
- Other uses:
 - ◆ Sensing elements (e.g. chemical sensors)
 - ◆ Really high-pitch guitars

Micromechanical filters

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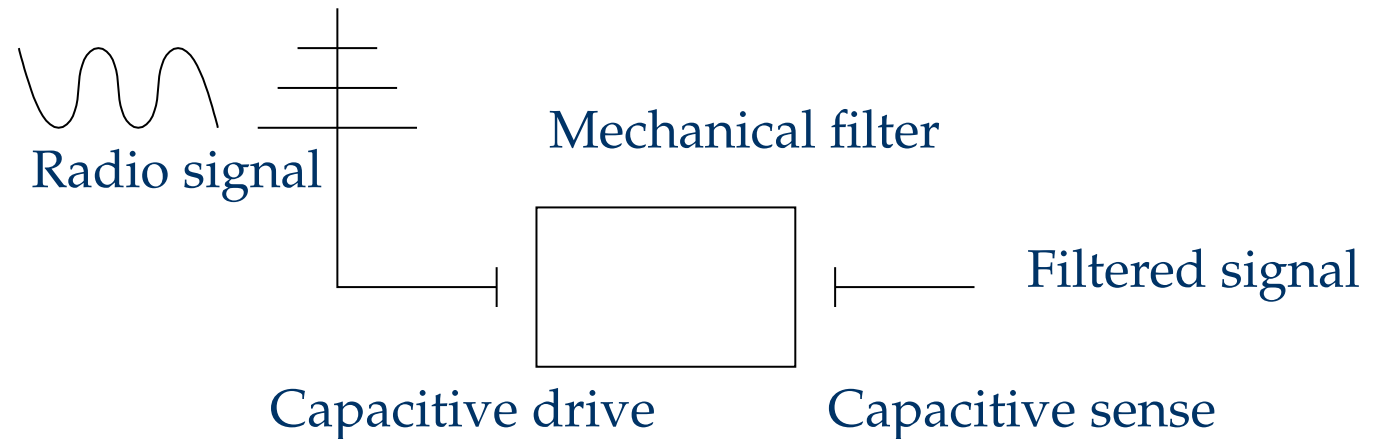
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- Mechanical high-frequency (high MHz-GHz) filter
 - ◆ Your cell phone is mechanical!
- Advantage over quartz surface acoustic wave filters
 - ◆ Integrated into chip
 - ◆ Low power

Success \implies “Calling Dick Tracy!”

Damping and Q

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- Want to minimize damping
 - ◆ Electronic filters have too much
 - ◆ Understanding of damping in MEMS resonators is lacking
- Engineers want one number: Q
 - ◆ Non-dimensionalized damping in a one-variable system:

$$\frac{d^2u}{dt^2} + Q^{-1} \frac{du}{dt} + u = F(t)$$

- ◆ For a resonant mode with frequency $\omega \in \mathbb{C}$:

$$Q := \frac{\Re(\omega)}{2\Im(\omega)} = \frac{\text{Stored energy}}{\text{Energy loss per radian}}$$

- Goal: Make Q big

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Conclusions

- Fluid damping
 - ◆ Air is a viscous fluid ($Re \ll 1$)
 - ◆ Can operate in a vacuum
 - ◆ Shown not to dominate in many RF designs
- Anchor loss
 - ◆ Elastic waves radiate from structure
- Thermoelastic damping
 - ◆ Volume changes induce temperature change
 - ◆ Diffusion of heat leads to mechanical loss
- Material losses (catch-all)
 - ◆ Low intrinsic losses in silicon, diamond, germanium, etc.
 - ◆ Terrible material losses in metals

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Disk resonator

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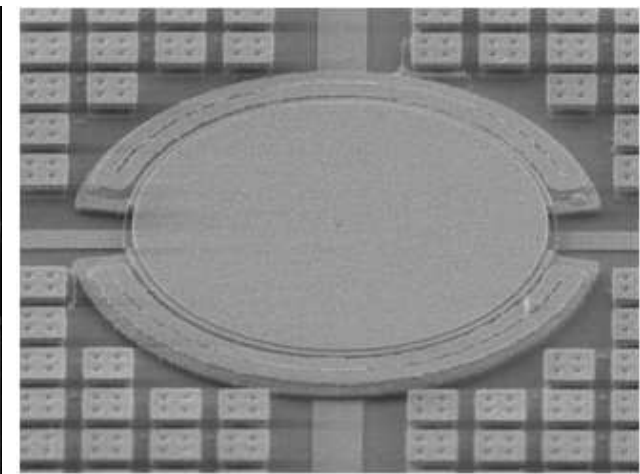
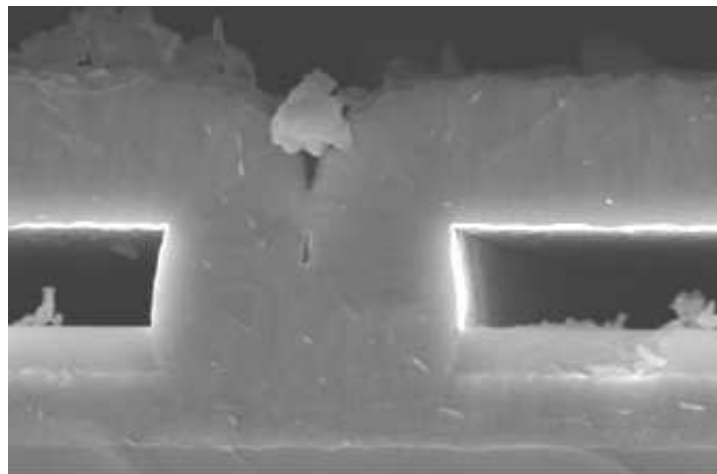
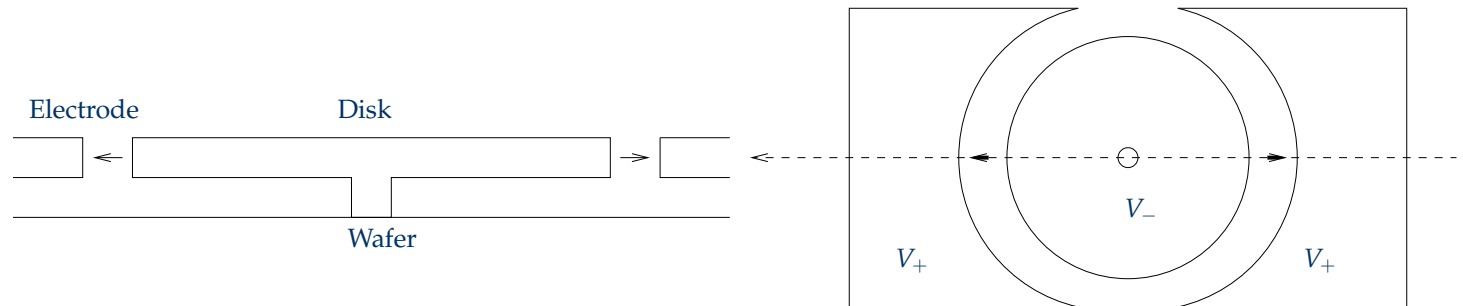
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- SiGe disk resonators built by E. Quévy
- Axisymmetric model with bicubic mesh, about 10K nodal points

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Conclusions

- Goal: Understand energy loss in this resonator
- Dominant loss is elastic radiation from anchor.
 - Disk resonator is much smaller than substrate
 - Very little energy leaving the post is reflected back
 - ◆ Substrate is semi-infinite from disk's perspective
 - Possible semi-infinite models
 - ◆ Matched asymptotic modes
 - ◆ Dirichlet-to-Neumann maps
 - ◆ Boundary dampers
 - ◆ Perfectly matched layers

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Perfectly matched layers

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- Apply a complex coordinate transformation
- Generates a non-physical absorbing layer
- No impedance mismatch between the computational domain and the absorbing layer
- Idea works with general linear wave equations
 - ◆ First applied to Maxwell's equations (Bereng er 95)
 - ◆ Similar idea introduced earlier in quantum mechanics (*exterior complex scaling*, Simon 79)

Scalar wave example

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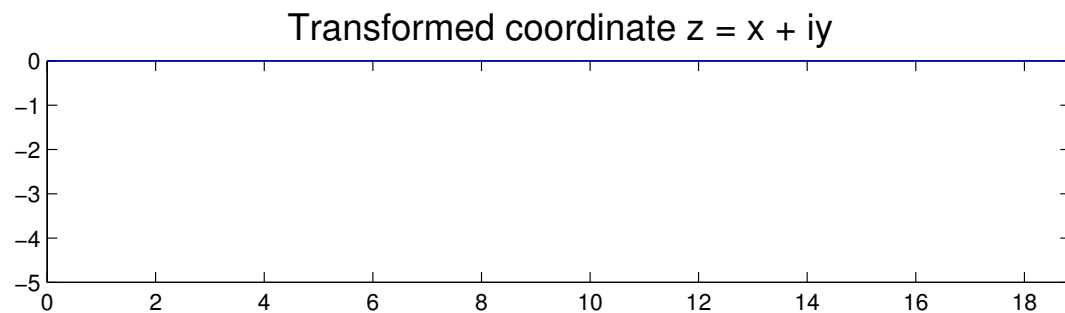
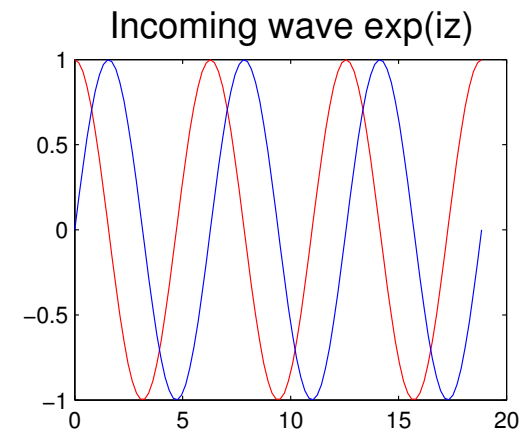
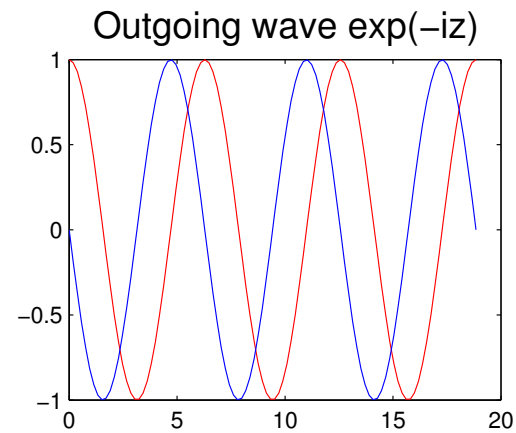
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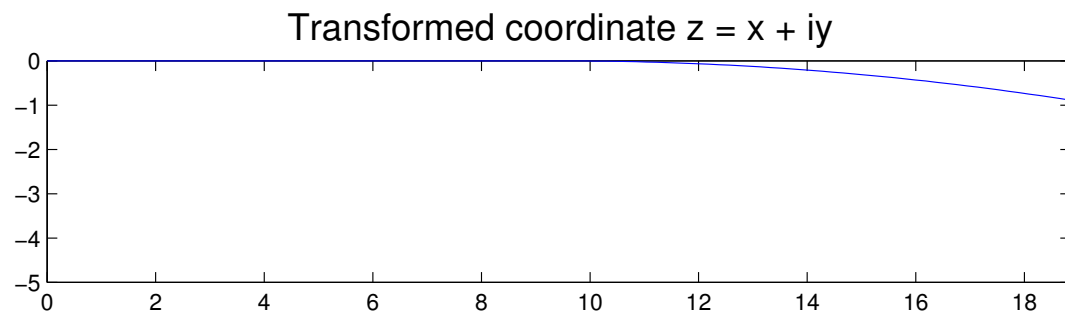
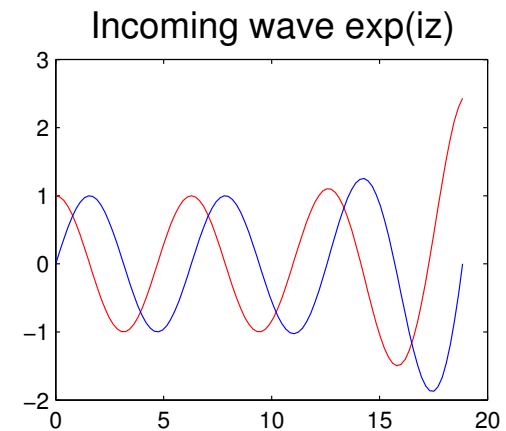
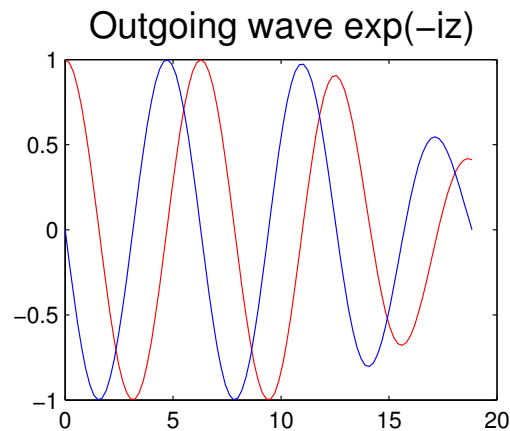
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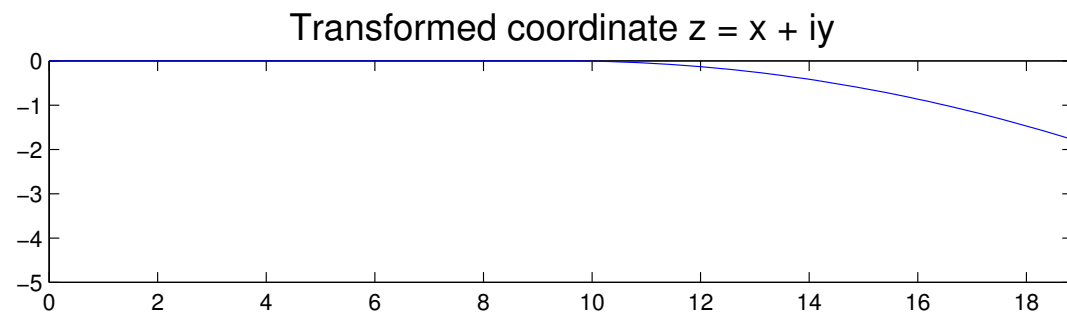
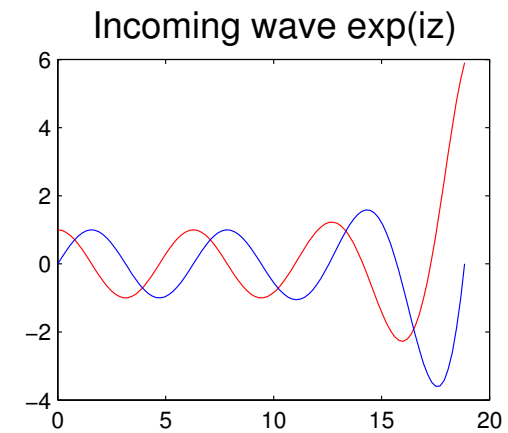
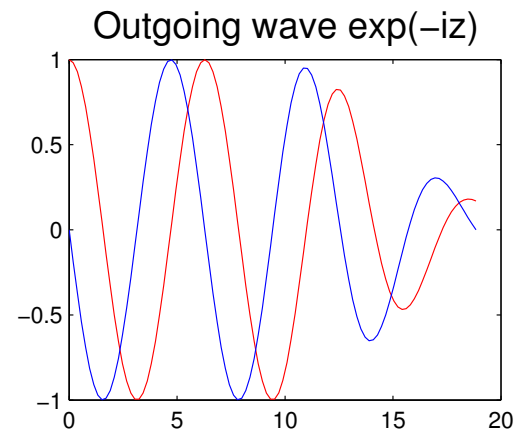
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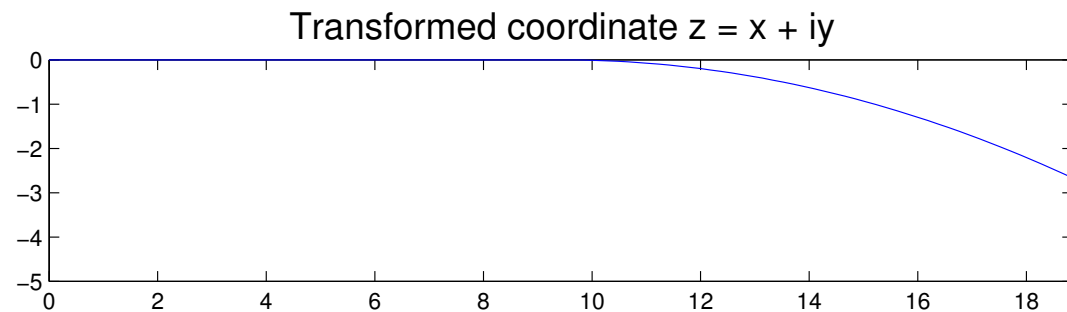
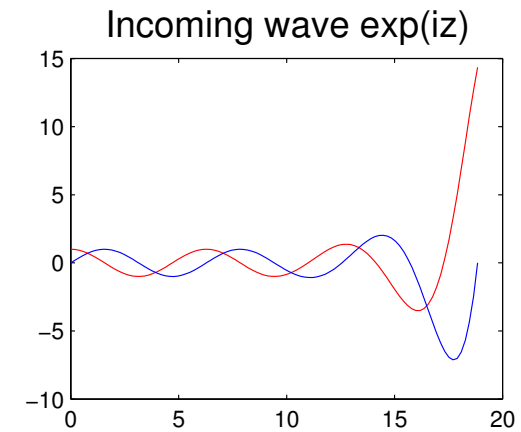
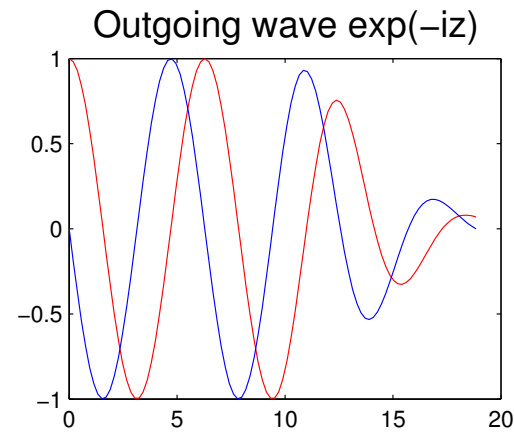
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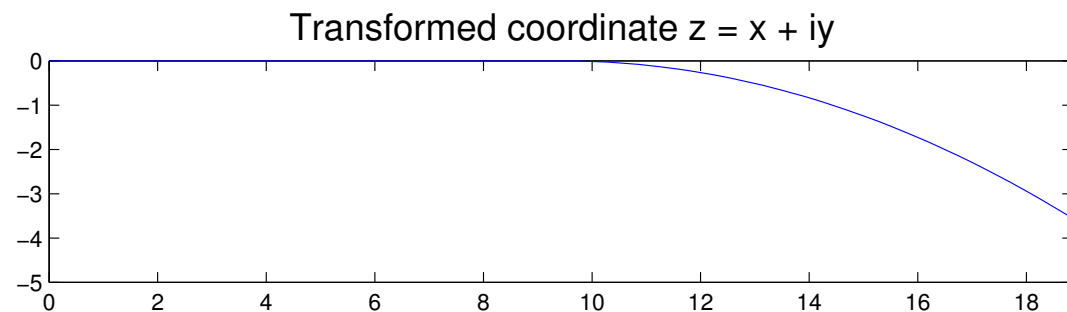
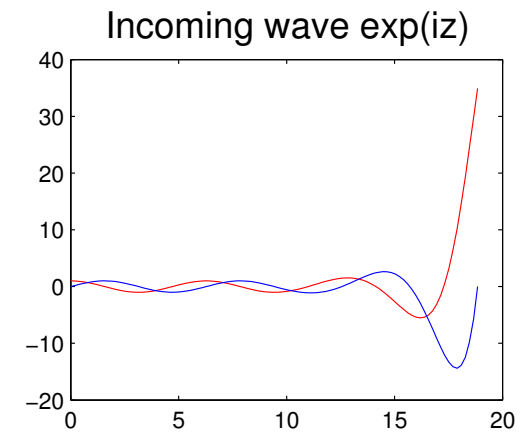
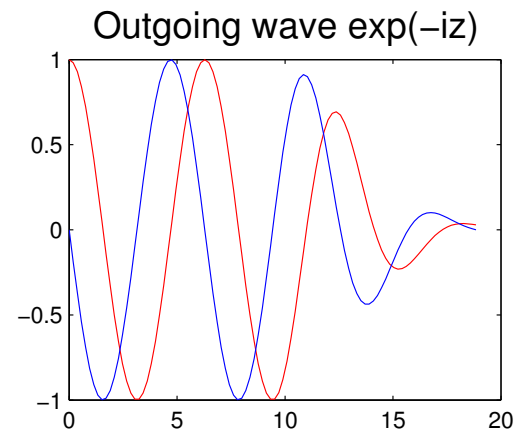
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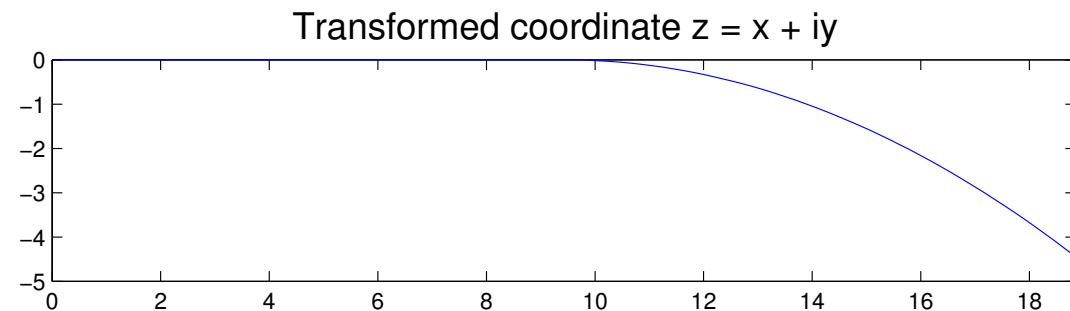
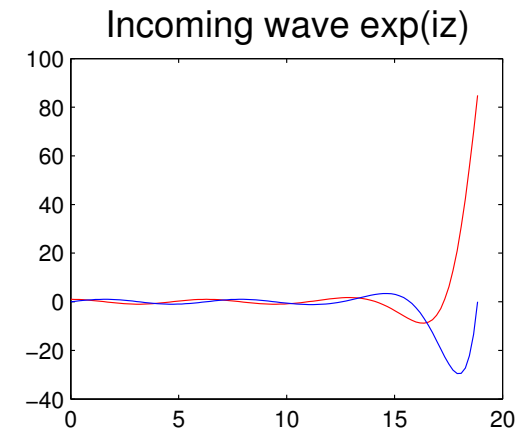
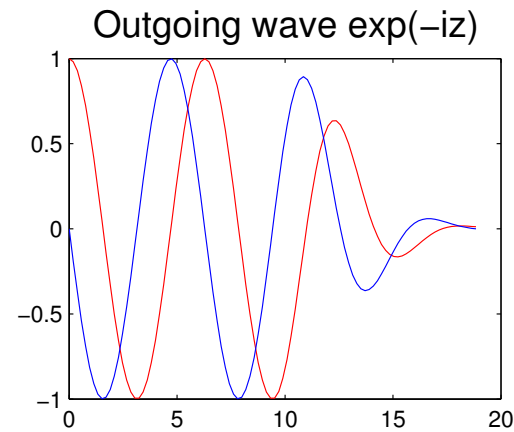
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Clamp solution at transformed end to isolate outgoing wave.

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Weak form of time-harmonic elasticity equations:

$$-\omega^2 \int_{\Omega} \rho w \cdot u \, d\Omega + \int_{\Omega} \epsilon(w) : \mathbf{C} : \epsilon(u) \, d\Omega = \int_{\Gamma} w \cdot t \, d\Gamma$$

Weak form of time-harmonic PML equation:

$$-\omega^2 \int_{\Omega} \rho w \cdot u \, J \, d\Omega + \int_{\Omega} \tilde{\epsilon}(w) : \mathbf{C} : \tilde{\epsilon}(u) \, J \, d\Omega = \int_{\Gamma} w \cdot \tilde{t} \, J \, d\Gamma$$

Bubnov-Galerkin finite element discretization leads to

$$-\omega^2 M u + K u = F$$

But in PML case, M and K are *complex symmetric*.

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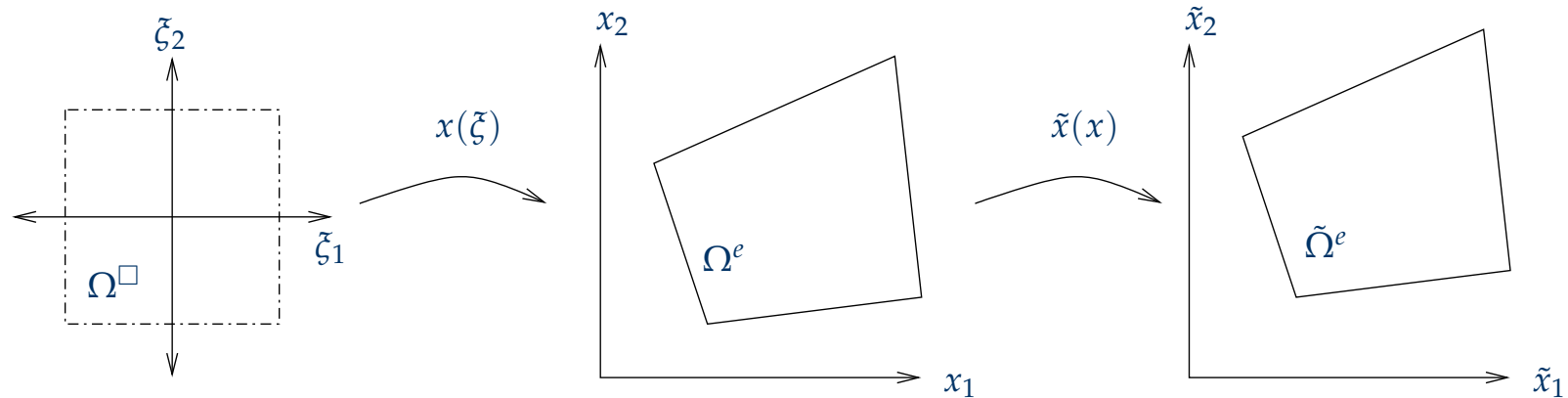
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Conclusions



- Isoparametric elements already use mapped integration
- View PML as an added coordinate transformation
 - ◆ Requires little modification to existing elements
 - ◆ Just transform derivatives and Jacobian determinant

Eigenstructure

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- Complex symmetry implies row and column eigenvectors are (non-conjugated) transposes.
- Can therefore achieve second-order accuracy with a modified Rayleigh quotient:

$$\theta(v) = (v^T K v) / (v^T M v)$$

- It *is* possible to have $v^T M v \approx 0$
 - ◆ Propagating modes (continuous spectrum)
 - ◆ Not the modes of interest for resonators

Perturbation analysis

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Know first-order perturbation behavior of eigenvalues:

$$(\omega + \delta\omega)^2 = \frac{v^T (K + \delta K) v}{v^T (M + \delta M) v}$$

Useful for sensitivity analysis.

Model reduction

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Conclusions

Would like a reduced model which

- Preserves second-order accuracy for converged eigs
- Keeps at least Arnoldi's accuracy otherwise
- Is physically meaningful

Idea:

- Build an Arnoldi basis V
- Double the size: $W = \text{orth}([\Re(V), \Im(V)])$
- Use W as a projection basis
- Resulting system is still a Galerkin approximation with real shape functions for the continuum PML equations

Q variation

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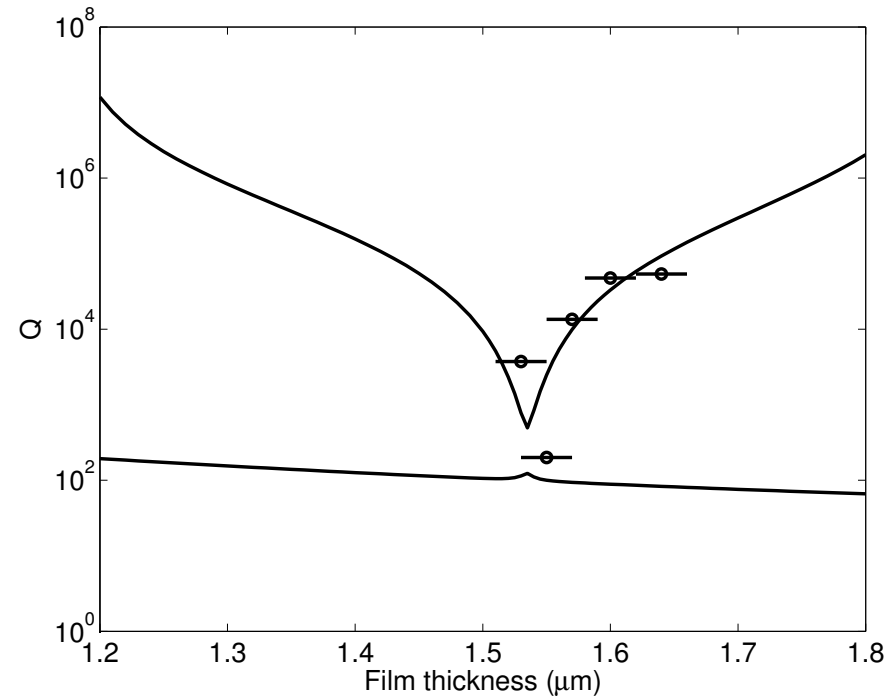
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Conclusions



- Compute complex frequencies by shift-and-invert Arnoldi with an analytically determined shift
- Surprising variation – experimentally observed – in Q as film thickness changes!

Effect of varying film thickness

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» Q variation

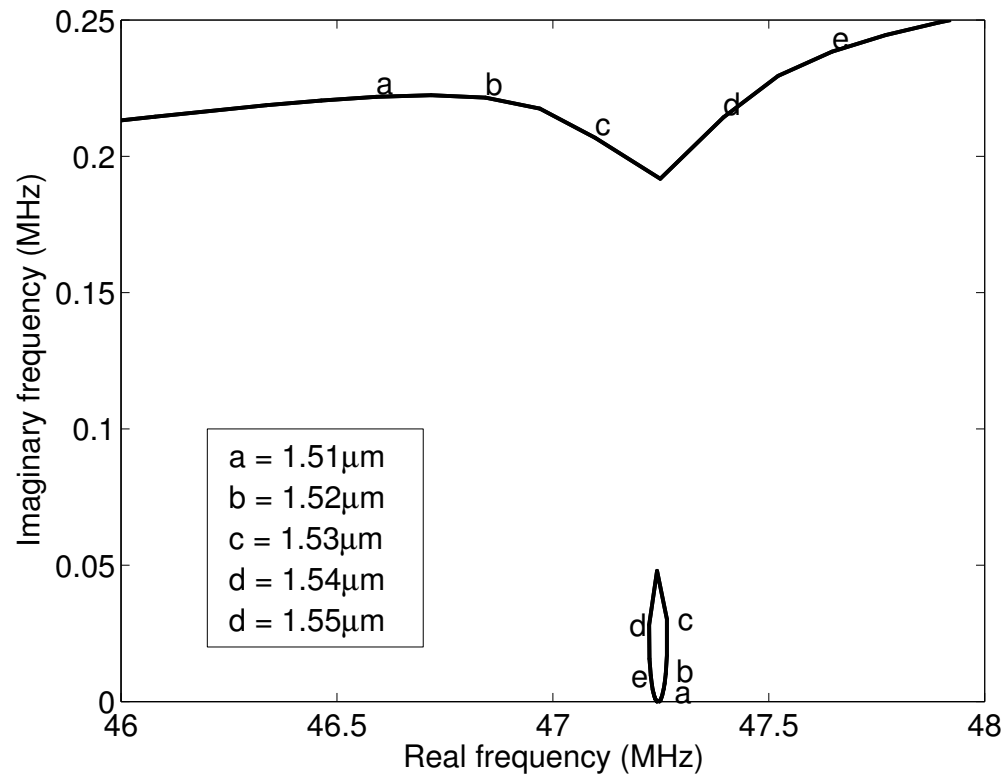
» Effect of varying film thickness

» Truth in advertising

Thermoelastic damping

Filter design

Conclusions



- Sudden dip in Q comes from an interaction between a (mostly) bending mode and a (mostly) radial mode
- Non-normal interaction between the modes

Truth in advertising

» Outline

MEMS Basics

Anchor loss

» Disk resonator

» Substrate model

» Perfectly matched layers

» Scalar wave example

» PML weak form

» Finite elements

» Eigenstructure

» Perturbation analysis

» Model reduction

» Q variation

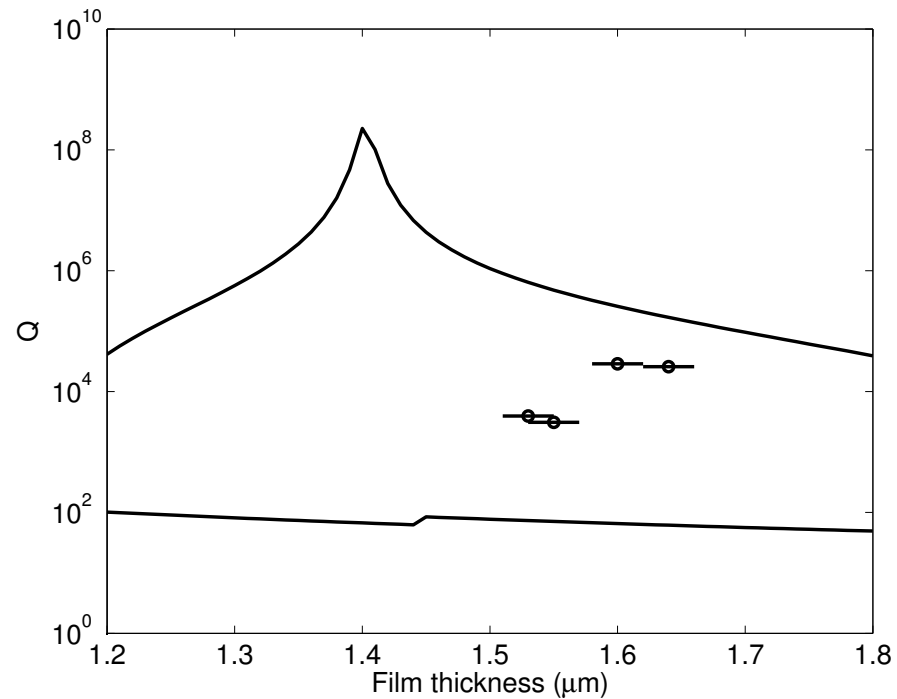
» Effect of varying film thickness

» Truth in advertising

Thermoelastic damping

Filter design

Conclusions



Data from a set of $30\mu\text{m}$ radius disks.

Thermoelastic damping (TED)

u is displacement and $T = T_0 + \theta$ is temperature

$$\sigma = C\epsilon - \beta\theta 1$$

$$\rho u_{tt} = \nabla \cdot \sigma$$

$$\rho c_v \theta_t = \nabla \cdot (\kappa \nabla \theta) - \beta T_0 \text{tr}(\epsilon_t)$$

- Volumetric strain rate drives energy transfer from mechanical to thermal domain
 - ◆ Irreversible diffusion \implies mechanical damping
 - ◆ Not often an important factor at the macro scale
 - ◆ Recognized source of damping in microresonators
- Zener: semi-analytical approximation for TED in beams
- We consider the fully coupled system

» Outline

MEMS Basics

Anchor loss

Thermoelastic damping

» Thermoelastic damping (TED)

» Nondimensionalization

» Scaling analysis

» Discrete mode equations

» Perturbation computation

» Comparison to Zener's model

Filter design

Conclusions

Nondimensionalization

» Outline

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» Thermoelastic damping (TED)

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Conclusions

$$\begin{aligned}\sigma &= \hat{C}\epsilon - \zeta\theta\mathbf{1} \\ u_{tt} &= \nabla \cdot \sigma \\ \theta_t &= \eta \nabla^2 \theta - \text{tr}(\epsilon_t)\end{aligned}$$

$$\zeta := \left(\frac{\beta}{\rho c}\right)^2 \frac{T_0}{c_v} \text{ and } \eta := \frac{\kappa}{\rho c_v c L}$$

$$\text{Length} \sim L$$

$$\text{Time} \sim L/c, \text{ where } c = \sqrt{E/\rho}$$

$$\text{Temperature} \sim T_0 \frac{\beta}{\rho c_v}$$

Scaling analysis

» Outline

MEMS Basics

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Thermoelastic damping

» Thermoelastic damping (TED)

» Nondimensionalization

» **Scaling analysis**

» Discrete mode equations

» Perturbation computation

» Comparison to Zener's model

Filter design

Conclusions

$$\begin{aligned}\sigma &= \hat{C}\epsilon - \tilde{\zeta}\theta\mathbf{1} \\ u_{tt} &= \nabla \cdot \sigma \\ \theta_t &= \eta \nabla^2 \theta - \text{tr}(\epsilon_t)\end{aligned}$$

$$\tilde{\zeta} := \left(\frac{\beta}{\rho c}\right)^2 \frac{T_0}{c_v} \text{ and } \eta := \frac{\kappa}{\rho c_v c L}$$

- Micron-scale poly-Si devices: $\tilde{\zeta}$ and η are $\sim 10^{-4}$.
- Small η leads to thermal boundary layers
- Linearize about $\tilde{\zeta} = 0$

Discrete mode equations

» Outline

MEMS Basics

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» Thermoelastic damping (TED)

» Nondimensionalization

» Scaling analysis

» Discrete mode equations

» Perturbation computation

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Conclusions

$$\sigma = \hat{C}\epsilon - \zeta\theta 1$$

$$u_{tt} = \nabla \cdot \sigma$$

$$\theta_t = \eta \nabla^2 \theta - \text{tr}(\epsilon_t)$$

$$\sigma = \hat{C}\epsilon - \zeta\theta 1$$

$$-\omega^2 u = \nabla \cdot \sigma$$

$$i\omega\theta = \eta \nabla^2 \theta - i\omega \text{tr}(\epsilon)$$

$$-\omega^2 M_{uu}u + K_{uu}u + K_{ut}\theta = 0$$

$$i\omega D_{tt}\theta + K_{tt}\theta + i\omega D_{tu}u = 0$$

Perturbation computation

» Outline

MEMS Basics

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» Thermoelastic damping (TED)

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» Perturbation computation

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Conclusions

$$\begin{aligned}-\omega^2 M_{uu}u + K_{uu}u + K_{ut}\theta &= 0 \\ i\omega D_{tt}\theta + K_{tt}\theta + i\omega D_{tu}u &= 0\end{aligned}$$

Approximate ω by perturbation about $K_{ut} = 0$:

$$\begin{aligned}-\omega_0^2 M_{uu}u_0 + K_{uu}u_0 &= 0 \\ i\omega_0 D_{tt}\theta_0 + K_{tt}\theta_0 + i\omega_0 D_{tu}u_0 &= 0\end{aligned}$$

Choose $v : v^T u_0 \neq 0$ and compute

$$\begin{bmatrix} (-\omega_0^2 M_{uu} + K_{uu}) & -2\omega_0 M_{uu}u_0 \\ v^T & 0 \end{bmatrix} \begin{bmatrix} \delta u \\ \delta \omega \end{bmatrix} = \begin{bmatrix} -K_{ut}\theta_0 \\ 0 \end{bmatrix}$$

Comparison to Zener's model

» Outline

MEMS Basics

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» Nondimensionalization

» Scaling analysis

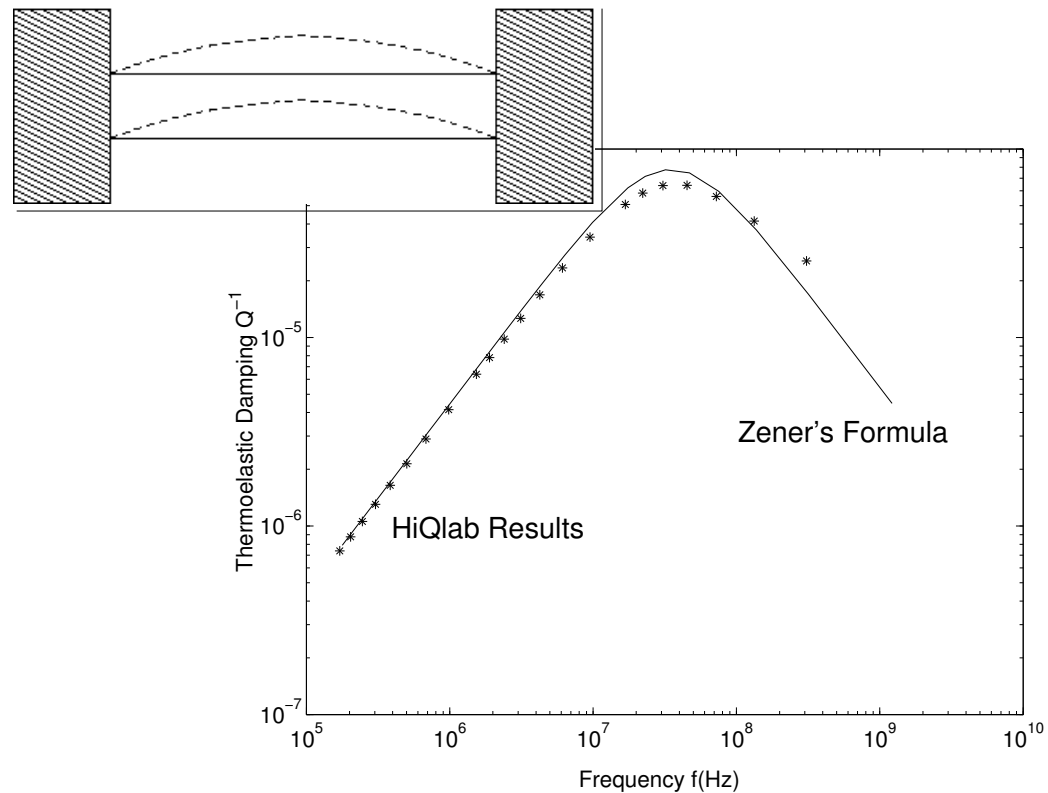
» Discrete mode equations

» Perturbation computation

» Comparison to Zener's model

Filter design

Conclusions



- Comparison of fully coupled simulation to Zener approximation over a range of frequencies
- Real and imaginary parts after first-order correction agree to about three digits with Arnoldi

Checkerboard resonator

» Outline

MEMS Basics

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Thermoelastic damping

Filter design

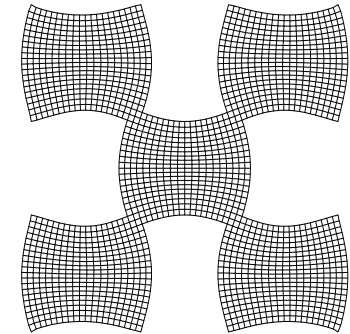
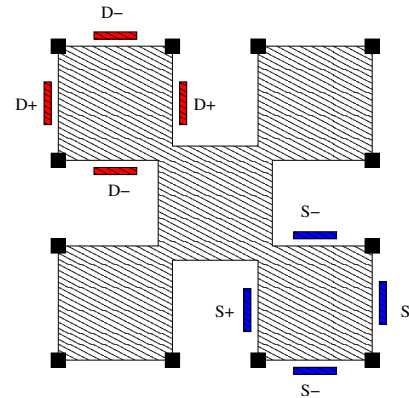
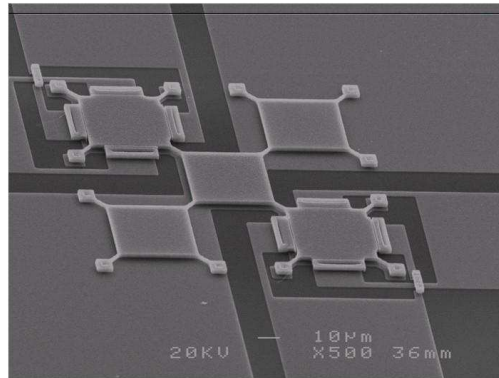
» Checkerboard resonator

» Checkerboard simulation

» Checkerboard measurement

» Transfer function optimization

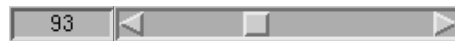
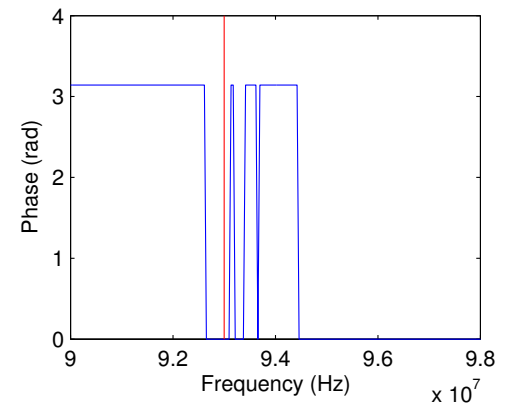
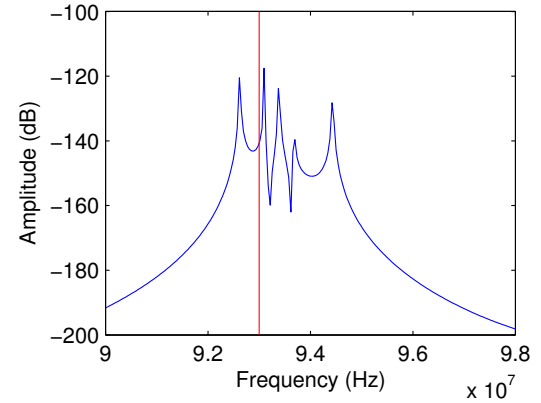
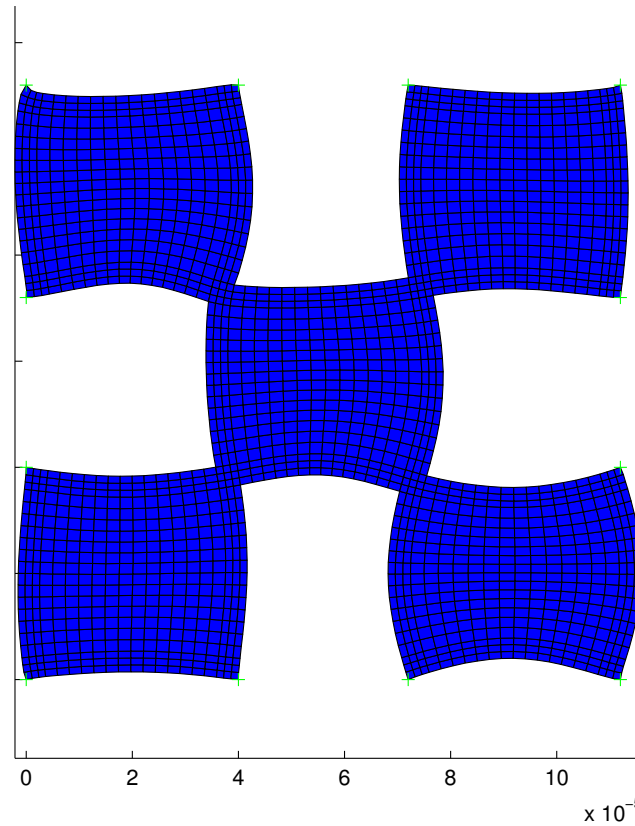
Conclusions



- Array of loosely coupled resonators
- Anchored at outside corners
- Excited at **northwest** corner
- Sensed at **southeast** corner
- Surfaces move only a few nanometers

Checkerboard simulation

- » Outline
- MEMS Basics
- Anchor loss
- Thermoelastic damping
- Filter design
- » Checkerboard resonator
- » Checkerboard simulation**
- » Checkerboard measurement
- » Transfer function optimization
- Conclusions



Checkerboard measurement

» Outline

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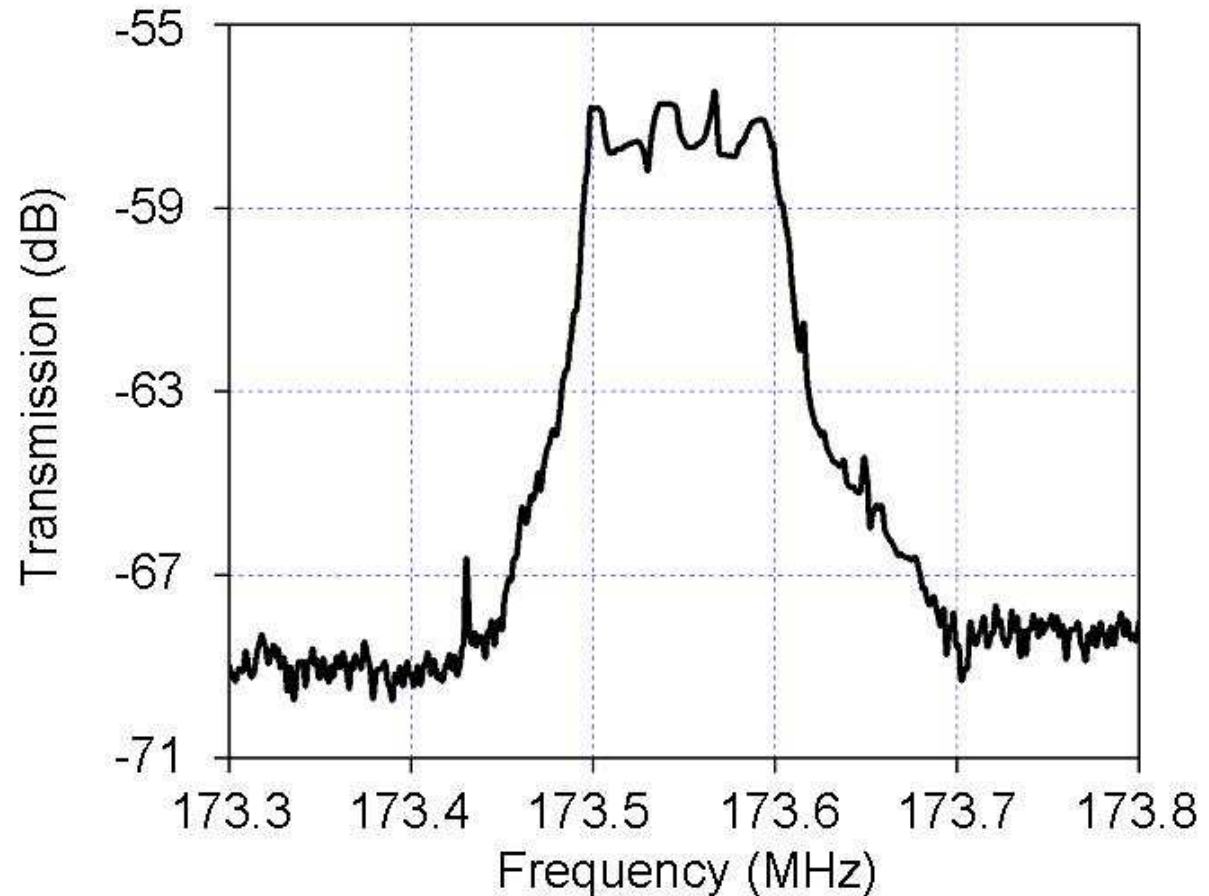
» Checkerboard resonator

» Checkerboard simulation

» **Checkerboard measurement**

» Transfer function optimization

Conclusions



S. Bhave, MEMS 05

Transfer function optimization

» Outline

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» Checkerboard resonator

» Checkerboard simulation

» Checkerboard measurement

» Transfer function optimization

Conclusions

- Choose geometry to make a good bandpass filter
- What is a “good bandpass filter?”
 - ◆ $|H(\omega)|$ is big on $[\omega_l, \omega_r]$
 - ◆ $|H(\omega)|$ is tiny outside this interval
- How do we optimize?
 - ◆ Overton’s gradient sampling method
 - ◆ Use Byers-Boyd-Balikrishnan algorithm for distance to instability to minimize $|H(\omega)|$ on $[\omega_l, \omega_r]$
 - ◆ Small Hamiltonian eigenproblem (with ROM)

Contributions

» Outline

MEMS Basics

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» Contributions

» The other talk

» Conclusions

- Mathematical
 - ◆ Reformulation of PML technology
 - ◆ Perturbation solution for thermoelastic damping
- Computer science
 - ◆ HiQLab, SUGAR, and FEAPMEX
- Engineering physics
 - ◆ Effects of mode interference in damping
 - ◆ Relative importance of anchor loss and TED

The other talk

» Outline

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» The other talk

» Conclusions

- CLAPACK
- Finding roots of polynomials
- Continuation of invariant subspaces for sparse problems
- Computer network tomography
- OceanStore and distributed system security
- Pontificating about floating point arithmetic

Conclusions

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MEMS Basics

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» Contributions

» The other talk

» Conclusions

- RF MEMS are a great source of problems
 - ◆ Interesting applications
 - ◆ Interesting physics (and not altogether understood)
 - ◆ Interesting numerical mathematics

<http://www.cs.berkeley.edu/~dbindel/feapmex.html>

<http://www.cs.berkeley.edu/~dbindel/hiqlab>

<http://bsac.berkeley.edu/cadtools/sugar/sugar/>

Role of simulation

» Outline

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Backup slides

» Role of simulation

» Shear ring resonator

» Mode tracking

» Mode tracking in a shear resonator

» Thermoelastic boundary layer

HiQLab: Modeling RF MEMS

- Explore fundamental device physics
 - ◆ Particularly details of damping
- Detailed finite element modeling
- Reduced models eventually to go into SUGAR

SUGAR: “Be SPICE to the MEMS world”

- Fast enough for early design stages
- Simple enough to attract users
- Support design, analysis, optimization, synthesis
- Verify models by comparison to measurement

Shear ring resonator

» Outline

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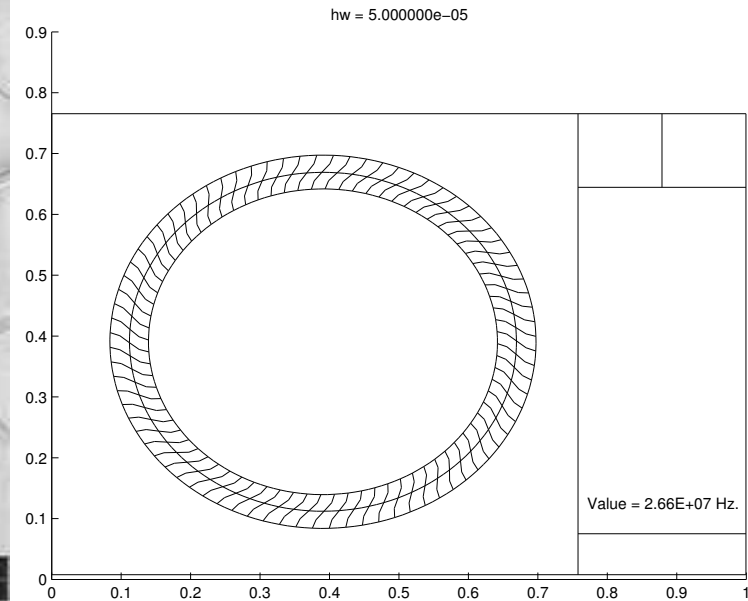
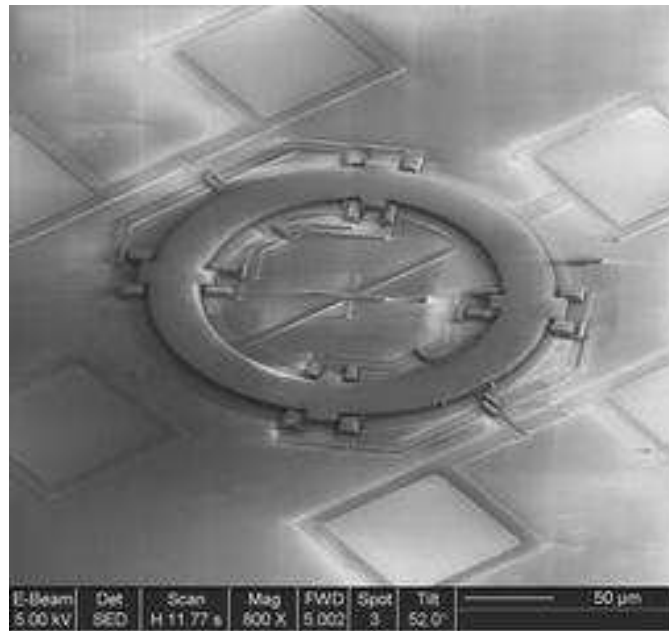
» Role of simulation

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- Ring is driven in a shearing motion
- Can couple ring to other resonators
- How do we track the desired mode?

Mode tracking

» Outline

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Find a continuous solution to

$$\left(K(s) - \omega(s)^2 M(s) \right) u(s) = 0.$$

- K and M are symmetric and $M > 0$
- Eigenvectors are M -orthogonal
- Perturbation theory gives good shifts
- Look if $u(s+h)$ and $u(s)$ are on the same path by looking at $u(s+h)^T M(s+h)u(s)$
- Many more subtleties in the nonsymmetric case
 - ◆ Focus of the *CIS algorithm*

Mode tracking in a shear resonator

» Outline

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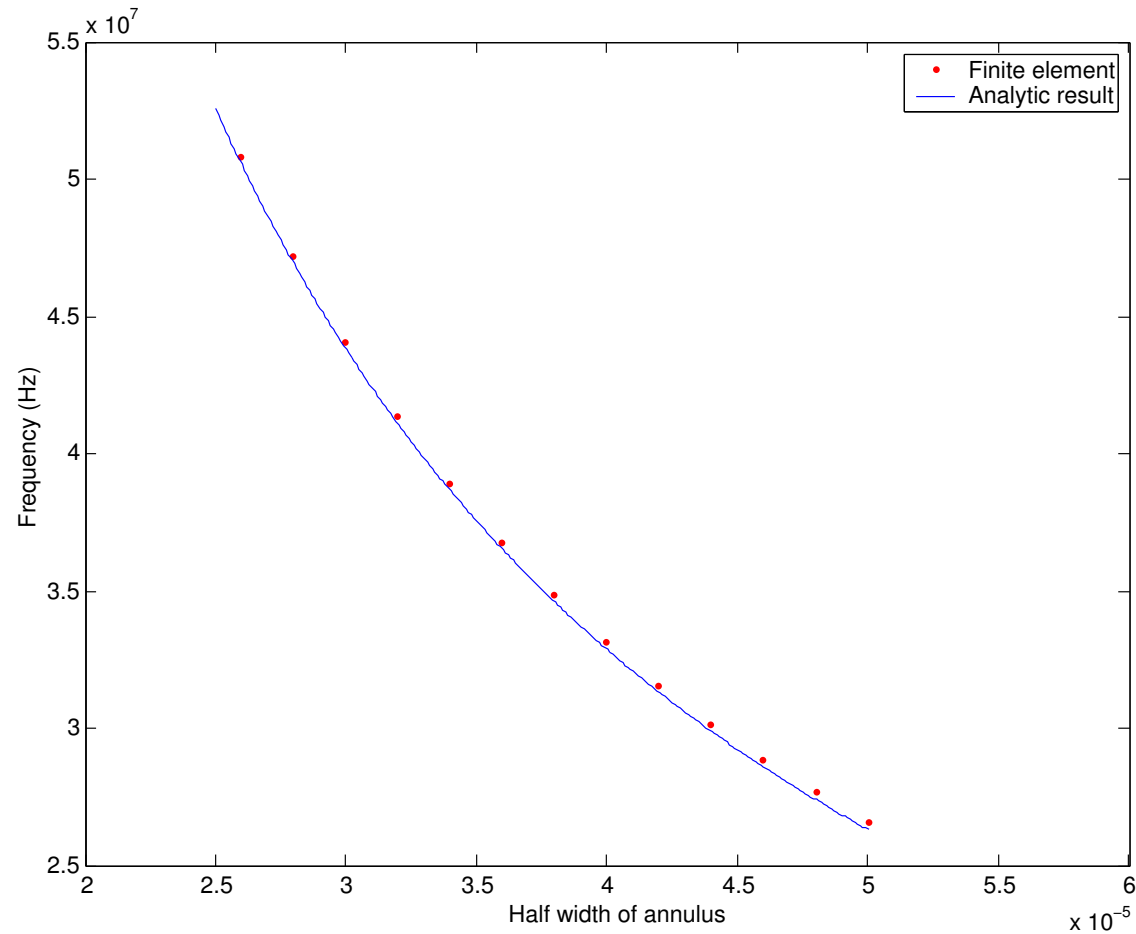
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Thermoelastic boundary layer

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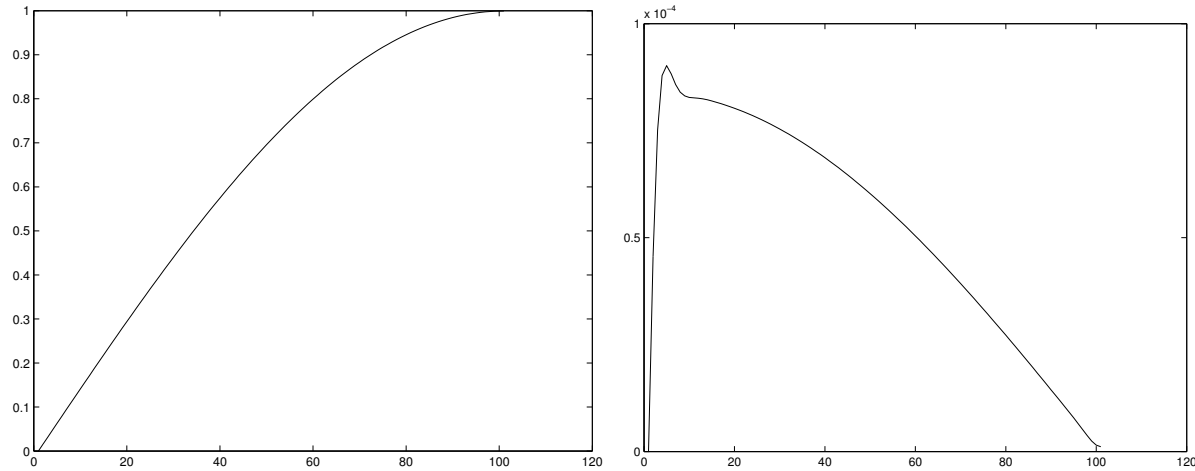
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- One-dimensional test problem (longitudinal mode in a bar)
- Fixed temperature and displacement at left
- Free at right